

L Number	Hits	Search Text	DB	Time stamp
1	542676	mill\$3 or micromachin\$3	USPAT; US-PGPUB	2004/04/05 10:38
2	23437	((mill\$3 or micromachin\$3) and deposit and ion	USPAT; US-PGPUB	2004/04/05 10:38
3	9919	((mill\$3 or micromachin\$3) and deposit and ion) and vacuum	USPAT; US-PGPUB	2004/04/05 10:38
4	3837	((mill\$3 or micromachin\$3) and deposit and ion) and vacuum) and electrode	USPAT; US-PGPUB	2004/04/05 10:38
5	2026	((mill\$3 or micromachin\$3) and deposit and ion) and vacuum) and electrode) and detect\$4	USPAT; US-PGPUB	2004/04/05 10:38
6	737	((mill\$3 or micromachin\$3) and deposit and ion) and vacuum) and electrode) and detect\$4) and lens\$2	USPAT; US-PGPUB	2004/04/05 10:38
7	657	((mill\$3 or micromachin\$3) and deposit and ion) and vacuum) and electrode) and detect\$4) and lens\$2) and imag\$4	USPAT; US-PGPUB	2004/04/05 10:38
8	657	((mill\$3 or micromachin\$3) and deposit and ion) and vacuum) and electrode) and detect\$4) and lens\$2) and imag\$4) and deposit\$4	USPAT; US-PGPUB	2004/04/05 10:38
9	571	((mill\$3 or micromachin\$3) and deposit and ion) and vacuum) and electrode) and detect\$4) and lens\$2) and imag\$4) and deposit\$4) and ((deposit\$4 or remov\$4) near6 (target or sample or wafer or substrate))	USPAT; US-PGPUB	2004/04/05 10:38
11	140	((mill\$3 or micromachin\$3) and deposit and ion) and vacuum) and electrode) and detect\$4) and lens\$2) and imag\$4) and deposit\$4) and ((deposit\$4 or remov\$4) near6 (target or sample or wafer or substrate))) and (focus\$4 near4 beam)	USPAT; US-PGPUB	2004/04/05 10:38
16	1524	((focus\$3 adj ion adj beam) and deposit\$4) and (micromachine or mill\$3)	USPAT	2004/04/05 10:38
17	554	((focus\$3 adj ion adj beam) and deposit\$4) and (micromachine or mill\$3)	USPAT	2004/04/05 10:38
18	178	((focus\$3 adj ion adj beam) and deposit\$4) and (micromachine or mill\$3) and lens\$2	USPAT	2004/04/05 10:38
19	138	((focus\$3 adj ion adj beam) and deposit\$4) and (micromachine or mill\$3) and lens\$2) and imag\$4	USPAT	2004/04/05 10:38
22	825	((focus\$3 adj ion adj beam) and deposit\$4) and (micromachine or mill\$3)	USPAT; US-PGPUB	2004/04/05 10:39
23	2266	((focus\$3 adj ion adj beam) and deposit\$4	USPAT; US-PGPUB	2004/04/05 10:39
24	855	((focus\$3 adj ion adj beam) and deposit\$4) and (micromachine or mill\$3)	USPAT; US-PGPUB	2004/04/05 10:39
25	282	((focus\$3 adj ion adj beam) and deposit\$4) and (micromachine or mill\$3) and lens\$2	USPAT; US-PGPUB	2004/04/05 10:39
29	42041	((mill\$3 or micromachin\$3 or etch\$3) and deposit and ion	USPAT; US-PGPUB	2004/04/05 10:40
30	654	((mill\$3 or micromachin\$3 or etch\$3) and deposit and ion) and (focus\$3 adj ion adj beam)	USPAT; US-PGPUB	2004/04/05 10:40
31	1856	((mill\$3 or micromachin\$3 or etch\$3) and deposit and ion) and (focus\$3 near2 beam)	USPAT; US-PGPUB	2004/04/05 10:40
32	296	((mill\$3 or micromachin\$3 or etch\$3) and deposit and ion) and (focus\$3 near2 beam)) and (shap\$4 near3 (beam or aperture))	USPAT; US-PGPUB	2004/04/05 10:40
33	200	((mill\$3 or micromachin\$3 or etch\$3) and deposit and ion) and (focus\$3 near2 beam)) and (shap\$4 near3 (beam or aperture))) and lens\$3	USPAT; US-PGPUB	2004/04/05 10:40

34	152	(((((mill\$3 or micromachin\$3 or etch\$3) and deposit and ion) and (focus\$3 near2 beam)) and (shap\$4 near3 (beam or aperture))) and lens\$3) and vacuum	USPAT; US-PGPUB	2004/04/05 10:40
37	2266	((focus\$3 adj ion adj beam) and deposit\$4)	USPAT; US-PGPUB	2004/04/05 10:40
38	733	((focus\$3 adj ion adj beam) and deposit\$4) and aperture	USPAT; US-PGPUB	2004/04/05 10:40
40	2277	((mill\$3 or micromachin\$3) and deposit and ion) and aperture	USPAT; US-PGPUB	2004/04/05 10:40
41	56	((mill\$3 or micromachin\$3) and deposit and ion) and aperture) and (rectang\$5 near3 aperture)	USPAT; US-PGPUB	2004/04/05 10:40
43	124	((mill\$3 or micromachin\$3) and deposit and ion) and aperture) and ((rectang\$5 or square) near8 aperture)	USPAT; US-PGPUB	2004/04/05 10:40
45	843	250/309	USPAT; US-PGPUB	2004/04/05 10:40
46	2661	250/306	USPAT; US-PGPUB	2004/04/05 10:40
49	1	gerlach-robert.in.	USPAT	2004/04/05 10:40
50	0	vandermast-karl.in.	USPAT; US-PGPUB	2004/04/05 10:40
57	2247	250/307	USPAT; US-PGPUB	2004/04/05 10:40
58	1187	250/492.21	USPAT; US-PGPUB	2004/04/05 10:40
59	2225	250/492.1	USPAT; US-PGPUB	2004/04/05 10:40
61	542685	mill\$3 or micromachin\$3 or overmill\$3	USPAT; US-PGPUB	2004/04/05 10:40
62	23437	(mill\$3 or micromachin\$3 or overmill\$3) and deposit and ion	USPAT; US-PGPUB	2004/04/05 10:40
63	2175	((mill\$3 or micromachin\$3 or overmill\$3) and deposit and ion) and (current near2 density)	USPAT; US-PGPUB	2004/04/05 10:40
65	3	((mill\$3 or micromachin\$3 or overmill\$3) and deposit and ion) and (current near2 density)) and (\$4Guass\$4 or (non adj gauss\$4))	USPAT; US-PGPUB	2004/04/05 10:40
67	40	ion and overmill\$4	USPAT	2004/04/05 10:40
69	56	ion and overmill\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/05 10:40
10	25	(((((((((mill\$3 or micromachin\$3) and deposit and ion) and vacuum) and electrode) and detect\$4) and lens\$2) and imag\$4) and deposit\$4) and ((deposit\$4 or remov\$4) near6 (target or sample or wafer or substrate))) and \$4Gauss\$4	USPAT; US-PGPUB	2004/04/05 10:41
12	87	(((((((((mill\$3 or micromachin\$3) and deposit and ion) and vacuum) and electrode) and detect\$4) and lens\$2) and imag\$4) and deposit\$4) and ((deposit\$4 or remov\$4) near6 (target or sample or wafer or substrate))) and (focus\$4 near4 beam)) and column	USPAT; US-PGPUB	2004/04/05 10:41
13	3	(US-5973295-\$ or US-5916424-\$ or US-5061850-\$).did.	USPAT	2004/04/05 10:41
14	6	5262617.pn. or 5186982.pn. or 5159171.pn. or 5151377.pn. or 51106150.pn. or 5099090.pn. or 4959112.pn.	USPAT	2004/04/05 10:41
15	4	"FIB-CVD"	USPAT	2004/04/05 10:41
20	98	(((((focus\$3 adj ion adj beam) and deposit\$4) and (micromachine or mill\$3)) and lens\$2) and imag\$4) and vacuum	USPAT	2004/04/05 10:41

35	50	(((((mill\$3 or micromachin\$3 or etch\$3) and deposit and ion) and (focus\$3 near2 beam)) and (shap\$4 near3 (beam or aperture))) and lens\$3) and vacuum) and imag\$3) and electrode	USPAT; US-PGPUB	2004/04/05 10:41
36	103	(((((mill\$3 or micromachin\$3 or etch\$3) and deposit and ion) and (focus\$3 near2 beam)) and (shap\$4 near3 (beam or aperture))) and lens\$3) and vacuum) and imag\$3	USPAT; US-PGPUB	2004/04/05 10:41
39	24	((((focus\$3 adj ion adj beam) and deposit\$4)) and aperture) and ("knife-edge" or knife)	USPAT; US-PGPUB	2004/04/05 10:41
42	3	((((mill\$3 or micromachin\$3) and deposit and ion) and aperture) and (rectang\$5 near3 aperture)) and knife	USPAT; US-PGPUB	2004/04/05 10:41
44	3	((((mill\$3 or micromachin\$3) and deposit and ion) and aperture) and ((rectang\$5 or square) near8 aperture)) and (knife same aperture)	USPAT; US-PGPUB	2004/04/05 10:41
47	11	(US-5973295-\$ or US-5916424-\$ or US-5061850-\$ or US-6177670-\$ or US-5952658-\$ or US-5852297-\$ or US-5583344-\$ or US-5151605-\$ or US-5120925-\$ or US-5389196-\$ or US-RE33193-\$.did.	USPAT	2004/04/05 10:41
48	1	4698236.pn.	USPAT	2004/04/05 10:41
51	1	gerlach-robert.in.	USPAT; US-PGPUB	2004/04/05 10:41
52	1	utlaut-mark.in.	USPAT; US-PGPUB	2004/04/05 10:41
53	3	tesch-paul.in.	USPAT; US-PGPUB	2004/04/05 10:41
54	19	young-richard.in.	USPAT; US-PGPUB	2004/04/05 10:41
55	3	chandler-clive.in.	USPAT; US-PGPUB	2004/04/05 10:41
56	47	van\$1der\$lmast	USPAT; US-PGPUB	2004/04/05 10:41
60	2	4698236.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/05 10:41
64	3	((((mill\$3 or micromachin\$3 or overmill\$3) and deposit and ion) and (current near2 density)) and (Guass\$4 or (non adj gauss\$4))	USPAT; US-PGPUB	2004/04/05 10:41
66	17	((((mill\$3 or micromachin\$3 or overmill\$3) and deposit and ion) and (current near2 density)) and ((\$4Guass\$4 or (non adj gauss\$4)) or (hollow near2 beam))	USPAT; US-PGPUB	2004/04/05 10:41
68	33	(ion and overmill\$4) and density	USPAT	2004/04/05 10:41
70	40	(ion and overmill\$4) and density	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/05 10:41
71	40	(ion and overmill\$4) and density	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/05 10:41
72	8	overmill\$4 and (current near3 density)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/05 10:41
73	104	(shap\$4 near2 beam) and (mill\$4 or overmill\$4) and (uniform near3 density)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/05 10:41

74	89	(shap\$4 near2 beam) and (mill\$3 or overmill\$4) and (uniform near3 density)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/04/05 10:41
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